

# **BSIM 4.6.1 - Release**

## **Enhancements over BSIM4.6.0**

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# Model Enhancements

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- Error in the derivative calculation for  $dV_{dseffCV\_dVb}$  is fixed within `b4ld.c`.
- Warning messages about the limits on `NOFF` and `VOFFCV` are removed in `b4check.c`.
- The C-V model is enhanced by adding a new definition for  $V_{gsteffCV}$  to improve the sub-threshold fitting.
- New Material Model is introduced for predictive modeling of non-SiO<sub>2</sub> insulator, non-poly Si gate and non-Si channel.
- Mobility model, GIDL/GISL and Poly depletion models are made more predictive.

# Bug Fix : dVdseffCV\_dVb

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- Reported by Geoffery Coram (ADI)
- Error in the derivative calculation for dVdseffCV\_dVb fixed within b4ld.c.
- The following lines in the code have been modified :

## Capmod = 1

**OLD** :  $dVdseffCV\_dVb = dT0\_dVb * (1.0 - T5) + T5 * dT1\_dVb;$

**NEW** :  $dVdseffCV\_dVb = dT0\_dVb * (T4 - T5) + T5 * dT1\_dVb;$

## Capmod=2

**OLD** :  $dVdseffCV\_dVb = dT0\_dVb * (1.0 - T5) + T5 * dT1\_dVb;$

**NEW** :  $dVdseffCV\_dVb = dT0\_dVb * (T4 - T5) + T5 * dT1\_dVb;$

# Changes to b4check.c

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- Warning messages about the limits on NOFF and VOFFCV have been removed.

# C-V Model

- A new  $V_{gsteffCV}$  definition is introduced into C-V model to improve sub-threshold fitting.
- Setting  $CVCHARGEMOD = 1$  activates the new  $V_{gsteffCV}$  calculation which is similar to the  $V_{gsteff}$  formulation in the I-V model.

$$V_{gsteffCV} = \frac{nv_t \ln \left( 1 + \exp \left( \frac{m^* (V_{gse} - V_{th})}{nv_t} \right) \right)}{m^* + nC_{oxe} \sqrt{\frac{2f_s}{qNDEPe_{Si}}} \exp \left( -\frac{(1-m^*)(V_{gse} - V_{th}) - V_{off}'}{nv_t} \right)}$$

$$m^* = 0.5 + \frac{\arctan(MINVCV)}{p} \quad V_{off}' = VOFFCV + \frac{VOFFCVL}{L_{eff}}$$

- Setting  $CVCHARGEMOD = 0$  defaults C-V model to BSIM4.6.0.
- 6 new parameters added :
  - $CVCHARGEMOD$ ,  $MINVCV$ ,  $LMINVCV$ ,  $WMINVCV$ ,  $PMINVCV$  and  $VOFFCVL$

# New Material Model

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- A new materials model is introduced with the following features:
  - Predictive modeling of
    - Non-SiO<sub>2</sub> insulator
    - Non-poly-Si gate
    - Non-silicon channel
  - Improved predictive models for GIDL/GISL leakage current, mobility degradation and short channel effects
  - A model selector (MTRLMOD) is used to turn on/off all the new materials parameters/equations, thus maintains backward compatibility

# New Materials Model : New Parameters

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- Model selector:
  - MTRLMOD : =1 activates the new-materials option and =0 (default) deactivates
- For non-poly-silicon gate:
  - PHIG : Gate work function
  - EPSRGATE : Dielectric constant of gate relative to vacuum ( = 0 deactivates poly depletion)
- For non-SiO2 gate-dielectric:
  - EOT : Equivalent SiO2 thickness
  - VDDEOT : Gate voltage at which EOT is measured
- For non-silicon channel material:
  - EASUB : Electron affinity of substrate
  - EPSRSUB : Dielectric constant of substrate relative to vacuum
  - NIOSUB : Intrinsic carrier concentration at T=300.15K
  - BGOSUB : Band-gap of substrate at T=0K
  - TBGASUB : First parameter of band-gap change due to temperature
  - TBGBSUB : Second parameter of band-gap change due to temperature
  - ADOS : Density of states parameter to control charge centroid
  - BDOS : Density of states parameter to control charge centroid

# Non-Silicon Channel Material

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- Define the temperature-dependent intrinsic carrier concentrations and the band gap with the new non-silicon parameters for MTRLMOD = 1.

$$E_{g0} = BG0SUB - \frac{TBGASUB * Tnom^2}{Tnom + TBGBSUB}$$

$$E_{g(300.15)} = BG0SUB - \frac{TBGASUB * 300.15^2}{300.15 + TBGBSUB}$$

$$n_i = NIOSUB * \left( \frac{Tnom}{300.15} \right)^{3/2} \cdot e^{\frac{E_{g(300.15K)} - E_{g0}}{2V_t}}$$

$$E_g = BG0SUB - \frac{TBGASUB * Temp^2}{Temp + TBGBSUB}$$

# Non-Silicon Channel Material

- For MTRLMOD = 1, replace the hard coded dielectric constant of 11.7 (for silicon) with EPSRSUB.
- Change hard coded ratio of channel and insulator dielectric-constants (3.0 for Si/SiO2), e.g.

$$litl = \sqrt{3.0 \cdot TOXE \cdot XJ} \longrightarrow litl = \sqrt{\frac{EPSRSUB \cdot EOT \cdot XJ}{3.9 * 8.854 * 10^{-12}}}$$

- Introduce two new parameters for charge centroid for non-silicon channel materials in both I-V and C-V models.

$$X_{dc} = \frac{ADOS \times 1.9 \times 10^{-9}}{1 + \left( \frac{Vgsteff + (VTH0 - VFB - \phi_s)}{2toxp} \right)^{0.7 \times BDOS}}$$

# Non-SiO<sub>2</sub> Dielectric Material

- Change hard coded ratio of channel and insulator dielectric-constants (3.0 for Si/SiO<sub>2</sub>), e.g.

$$litl = \sqrt{3.0 \cdot TOXE \cdot XJ} \longrightarrow litl = \sqrt{\frac{EPSRSUB \cdot EOT \cdot XJ}{3.9 * 8.854 * 10^{-12}}}$$

- For MTRLMOD = 1, use EOT (defined as the electrical oxide thickness at  $V_{gs} = VDDEOT$ ) to calculate oxide thickness at flatband voltage.

$$Toxp = EOT - \frac{3.9}{EPSRSUB} \cdot X_{dc}|_{V_{gs}=VDDEOT, V_{ds}=V_{bs}=0}$$

# Non-poly-Si gate Material

- Poly depletion is calculated using the following equation :

$$V_{gse} = VFB + \Phi_s + \frac{qe_{gate}NGATE}{coxe^2} \left( \sqrt{1 + \frac{2coxe^2(V_{gs} - VFB - \Phi_s)}{qe_{gate}NGATE}} - 1 \right)$$

where

$$\begin{aligned} e_{gate} &= EPSRGATE \cdot EPS0 && \text{for MTRLMOD} = 1 \\ &= EPSSI && \text{for MTRLMOD} = 0 \end{aligned}$$

- Setting EPSRGATE = 0 turns the poly depletion model off.

# Improved Mobility Model

- For MTRLMOD = 1, mobility degradation uses a new definition of vertical field.

$$E_{eff} = \frac{V_{gsteff} + 2V_{th} - 2 * BSIM4type * (PHIG - EASUB - E_g/2 + 0.45)}{EOT} \cdot \frac{3.9}{EPSRSUB}$$

- MOBMOD = 0 and MOBMOD = 1 are changed accordingly.

**MOBMOD = 0**

$$\mu_{eff} = \frac{U0 \cdot f(L_{eff})}{1 + (UA + UC \cdot V_{bseff}) E_{eff} + UB \cdot E_{eff}^2 + UD \left( \frac{V_{th} \cdot EOT}{V_{gsteff} + 2\sqrt{V_{th}^2 + 0.00001}} \right)^2}$$

**MOBMOD = 1**

$$\mu_{eff} = \frac{U0 \cdot f(L_{eff})}{1 + (UA \cdot E_{eff} + UB \cdot E_{eff}^2) (1 + UC \cdot V_{bseff}) + UD \left( \frac{V_{th} \cdot EOT}{V_{gsteff} + 2\sqrt{V_{th}^2 + 0.00001}} \right)^2}$$

# Improved GIDL/GISL Model

- For MTRLMOD = 1, the flat band voltage at Source/Drain is calculated using

$$V_{fbsd} = PHIG - \left( EASUB + \frac{Eg0}{2} - BSIM4type \cdot MIN \left( \frac{Eg0}{2}, V_t \ln \left( \frac{NSD}{ni} \right) \right) \right)$$

- For MTRLMOD = 1, GIDL/GISL is given by

$$I_{GIDL} = AGIDL \cdot W_{effCJ} \cdot Nf \cdot \frac{V_{ds} - V_{gse} - EGIDL + V_{fbsd}}{EOT \cdot \frac{EPSRSUB}{3.9}} \cdot \exp \left( -\frac{EOT \cdot \frac{EPSRSUB}{3.9} \cdot BGIDL}{V_{ds} - V_{gse} - EGIDL + V_{fbsd}} \right) \cdot \frac{V_{db}^3}{CGIDL + V_{db}^3}$$

$$I_{GISL} = AGISL \cdot W_{effCJ} \cdot Nf \cdot \frac{-V_{ds} - V_{gse} - EGISL + V_{fbsd}}{EOT \cdot \frac{EPSRSUB}{3.9}} \cdot \exp \left( -\frac{EOT \cdot \frac{EPSRSUB}{3.9} \cdot BGISL}{-V_{ds} - V_{gse} - EGISL + V_{fbsd}} \right) \cdot \frac{V_{sb}^3}{CGISL + V_{sb}^3}$$